

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**


Applicant : Masahiko NAKAMORI, et al.  
Appl. No. : 10/536,621  
Filed : May 26, 2005  
For : POLISHING PAD AND METHOD  
OF PRODUCING  
SEMICONDUCTOR DEVICE  
Examiner : Sylvia McCarthur  
Group Art Unit : 1763

**CERTIFICATE OF EFS WEB  
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I hereby certify that this correspondence, and any other attachment noted on the automated Acknowledgement Receipt, is being transmitted from within the Pacific Time zone to the Commissioner for Patents via the EFS Web server on:

September 7, 2007

(Date)



Katsuhiro Arai, Reg.43,315

**RESPONSE TO ELECTION/RESTRICTIONS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is in response to the Office communication from the Examiner mailed August 10, 2007.

**Remarks** begin on page 2 of this paper.